Datasheet: 739174-W17

Macroporous silicon membrane

Etching

Type: lift-off membrane  
Size: 6 inch  
Pitch: 1.5 µm trigonal  
Thickness: 46 µm membrane thickness  
Shape: straight  
Diameter: 1 µm

Postprocessing

- Membrane lift-off
- Laserdicing 20x 20 mm

Measurements

Top view

Side view

Remarks

- Lifted backsides are sensitive to mechanical handling. Abrasion of silicon nanotips is visible as brown “scratches” on the surface but have minor effect on the underlying pores. We suggest using vacuum tweezers on the front side. Depending on the thickness, flat tips with small diameters are preferred instead of suction cup tips to minimize mechanical stress.

- Please be aware: Membranes <50µm thickness may flip due to electrostatic forces while opening or closing transport boxes!

2020-02-19, B.Berg

(If not specified separately standard tolerances of ± 10% will apply)